

ATMI-513  
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J. [signature]**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE****In re United States Patent Application of:****Applicants: Ravi K. Laxman, et al.****Serial No.: 09/811,106****Date Filed: March 17, 2001****Title: Low Dielectric Constant Thin Films and  
Chemical Vapor Deposition Method of Making  
Same****Confirmation Number: 9357****Group Art Unit: 1621****Examiner: Samuel A. Barts****FACSIMILE TRANSMISSION CERTIFICATE**

It hereby is certified by the person identified below that this paper is being facsimile transmitted by such person to the Commissioner of Patents and Trademarks on the date specified, to the Assistant Commissioner for Patents, Washington, DC 20231, and Transmitted by Facsimile under the provisions of 37 CFR 1.6(d).

  
Maggie ChappuisAugust 12, 2003  
Date of Transmission703-308-4556  
Facsimile Number**RESPONSE TO JULY 29, 2003 OFFICE ACTION DATED JULY 29, 2003 IN  
U.S. PATENT APPLICATION 09/811,106**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to an Office Action dated July 29, 2003, applicant respectfully requests consideration of the subsequent remarks.